

ABSTRACT

An optoelectronic process for inspection of an area of revolution of a receptacle presenting an axis of revolution, includes:

- illumination of the surface to be inspected using a lighting system presenting an axis of revolution that is located in the extension of the axis of revolution of the receptacle,
- formation of an image of the inspected surface using a camera, and analysis of the image formed with a view to checking the characteristics of the surface to be inspected.

The illumination is over at least three angular sectors, each emitting a given radiation spectrum that is separate from all the spectra of the other sectors. Only the light rays returned by the surface to be inspected are selected and one of the said given radiation spectra are presented to eliminate the parasitic light rays whose radiation spectrum does not correspond to that selected for the said angular sector.